



## Subject card

Subject name and code	Optical systems for automatic diagnostics and process monitoring, PG_00062774						
Field of study	Technologies for Industry 5.0						
Date of commencement of studies	October 2025		Academic year of realisation of subject		2027/2028		
Education level	first-cycle studies		Subject group		Obligatory subject group in the field of study Subject group related to scientific research in the field of study		
Mode of study	Full-time studies		Mode of delivery		at the university		
Year of study	3		Language of instruction		Polish		
Semester of study	6		ECTS credits		4.0		
Learning profile	general academic profile		Assessment form		exam		
Conducting unit	Department Of Metrology And Optoelectronics -> Faculty Of Electronics Telecommunications And Informatics -> Wydziały Politechniki Gdańskiej						
Name and surname of lecturer (lecturers)	Subject supervisor		dr hab. inż. Robert Bogdanowicz				
	Teachers						
Lesson types and methods of instruction	Lesson type	Lecture	Tutorial	Laboratory	Project	Seminar	SUM
	Number of study hours	15.0	0.0	15.0	15.0	0.0	45
	E-learning hours included: 0.0						
Learning activity and number of study hours	Learning activity	Participation in didactic classes included in study plan		Participation in consultation hours		Self-study	SUM
	Number of study hours	45		5.0		50.0	100
Subject objectives	The aim of the course is to acquire basic knowledge of optical monitoring and diagnostic methods in industrial systems. Students will learn to use optical methods to build diagnostic systems. In addition, the aim is to acquire the ability to correctly use the learned methods to design and implement basic diagnostic systems adapted to industry.						
Learning outcomes	Course outcome		Subject outcome		Method of verification		
	[K6_U02] identifies and solves problems related to signal processing and transmission, integrates measurement and control systems, manages electronic systems in the context of intelligent production processes		The student has a working knowledge of technological processes and monitoring tools using optical techniques.		[SU4] Assessment of ability to use methods and tools		
	[K6_K03] effectively, clearly and unambiguously conveys information, describes activities and communicates their results and opinions of a specialist engineer using appropriate communication methods and tools		The student interprets the phenomena occurring during optical diagnostics of a technological process and processes taking place in the life cycle of optical devices and systems, critically evaluates the functioning of existing solutions in the field of optical systems for automatic diagnostics and monitoring of industrial processes.		[SK3] Assessment of ability to organize work		
	[K6_W05] demonstrates practical knowledge related to technological processes, utilized devices and systems, has knowledge regarding selected processes monitoring tools		Student is able to deal with measurement errors and implement calibration and validation techniques. Communicates effectively, clearly and unambiguously, describes activities and communicates the results and opinions of the specialist engineer, using appropriate communication methods and tools, taking into account the specificities of optical solutions.		[SW1] Assessment of factual knowledge		

Subject contents	1, Measuring techniquesBasic measurement parameters obtained using optical methodsImportance and application in industry.2 Spectroscopy IIIntroduction to spectroscopy.Near-infrared (NIR), mid-infrared (MIR), Raman spectroscopy,Applications and significance.3 Spectroscopy IIMultiple linear regression (MLR).Fluorescence spectroscopy.UV/Vis spectroscopy.Comparison and applications.Interpretation and applications.4 Vision optical methodsVision systemsImage processing techniques.Pattern recognition in an industrial context.5 Measurement errors and uncertaintyCommon sources of error.Calibration and validation.		
Prerequisites and co-requisites			
Assessment methods and criteria	Subject passing criteria	Passing threshold	Percentage of the final grade
	Lecture	50.0%	40.0%
	Laboratory	50.0%	40.0%
	Project	59.0%	20.0%
Recommended reading	Basic literature	T. Pustelny: Physical and technical aspects of optoelectronic sensors, Wyd. Polit. Śląska, Gliwice 2005 Z. Kaczmarek: Światłowodowe czujniki i przetworniki pomiarowe (Optical fibre sensors and transducers), Publishing House PAK, Warsaw 2006Bishop C. M. Pattern Recognition and Machine Learning. Springer, 2006.Byrski, W. Observation and control in dynamic systems. Uczelniane Wydawnictwa Naukowo Dydaktyczne Akademii Górniczo Hutniczej w Krakowie, 2007.Jackson, J.E., A User's Guide to Principal Components, Wiley-Interscience (New York), 1991.Korbicz, J., Kościelny, J, Kowalczyk, Z., Cholewa, W. Process Diagnostics. Models, methods of artificial intelligence, applications. Wydawnictwa Naukowo Techniczne, Warszawa 2002.Korbicz J., Kościelny J.M. Modelling, diagnostics and master control of processes. Implementation in the DiaSter system. Wydawnictwa Naukowo Techniczne, Warszawa 2009.	
	Supplementary literature	Alpaydin, E. Introduction to Machine Learning. The MIT Press Cambridge, Massachusetts London, England 2010.  Berthold, M. Hand, D. J. Intelligent data analysis, an intruduction. Springer, 1999.  Bishop C. M. Neural Networks for Pattern Recognition. Oxford University Press, New York 1995.  Haykin, S. Neural Networks. A Comprehensive Foundation, Prentice Hall, 1999.  Venkatasubramanian, V., Rengaswamy, R., Kavuri, S.N. and Yin, K., A review of process fault detection and diagnosis Part I, Part II, Part I: Computers and Chemical Engineering 27, 2003.	
	eResources addresses	Adresy na platformie eNauczanie:	
	Example issues/ example questions/ tasks being completed	n/a	
Work placement	Not applicable		

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